

PATENT

Docket No.: ACT-307DVA

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Art Unit: 2814

For:

Examiner: Mai, Anh D.

Serial No.: 10/036,303

Filed: December 28, 2001

In Re Application of: Hawley

METHOD FOR FABRICATING AN MOS TRANSISTOR HAVING IMPROYED TOTAL RADIATION-INDUCED LEAKAGE CURRENT

Certificate of Mailing

I hereby pertify that this correspondence is being deposited with the United States Postal Service with sufficient postage as Kirst Class Mail, in an envelope addressed to MS Amendment, Commissioner for Patents, P.O. Box 1450,

RESPONSE TO OFFICE ACTION

MS Amendment Commissioner for Patents P.O. Box 1450 Alexandría, VA 22313-1450

Dear Sir:

mendment nixioner for Patents
30 x 1450
ndria, VA 22313-1450

Sir:

In response to the Office Action mailed December 26, 2002, kindly amend the above-identified application as follows.